

## **MIXDES2002**

***The 9th International Conference on Mixed Design of Integrated Circuits and Systems***  
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MIXDES 2002

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# **Multi-Level Modeling of Deep-Submicron MOSFETs and ULSI Circuits**

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# Presentation Outline

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**Overview**



**Xsim  
Compact Model**



**XSIM  
Mixed-Mode  
Simulator**



**DOUST  
Parameter  
Extraction**



**Conclusion**

## ***Challenges in multi-level modeling:***

from process through device/circuit to systems

## ***A technology-based compact model:***

General features, data requirement, parameter extraction,  
0.18- $\mu\text{m}$  technology prediction, process correlation

## ***An implicit mixed-signal simulator.***

Subcircuit expansion approach,  
Dynamic circuit partitioning and mode switching,  
Dynamic-delay model

## ***Xsim-DOUST-XSIM modeling environment:***

Design and Optimization of Ultra-Small Transistors  
Multi-level modeling with dual-representation

Summary of our approach to multi-level modeling

# Challenges in Compact Modeling and Circuit Simulation

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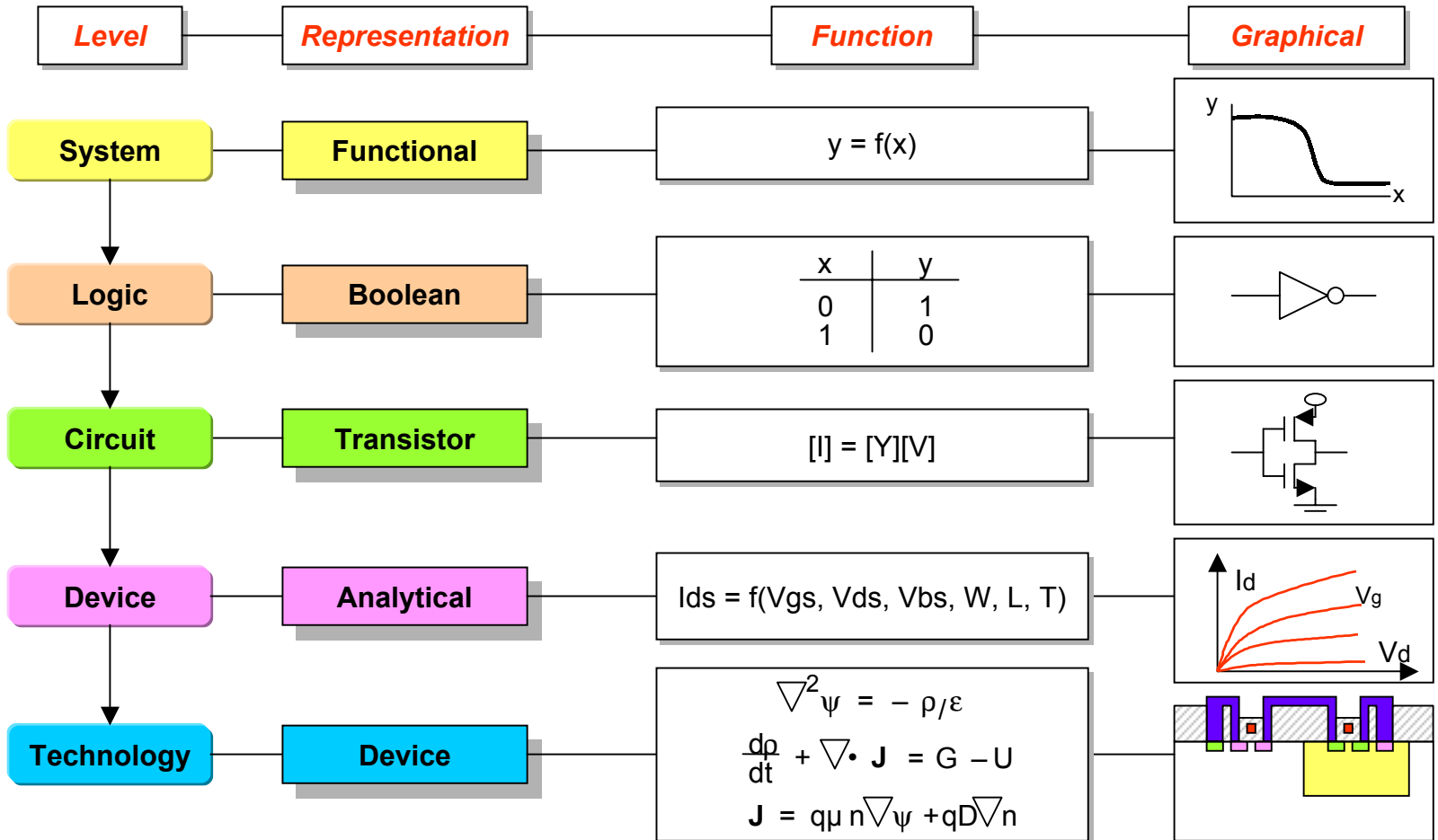
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- **ITRS (2001): one of the difficult challenges beyond 2007 (< 65 nm) in modeling — *Software Module Integration***
  - “Seamless integration of simulation modules with focus on interplay and interfacing of the modules in order to enhance design effectiveness”
  - *Example*: “A complete simulation chain linking process modeling, device modeling, compact model extraction, and library generation”
- **Real challenges in deep-submicron (DSM) modeling and simulation**
  - ***Experimental challenge***
    - Not in making one “short-channel” DSM transistor
    - But in making millions of the same transistor across different dies/wafers/lots
  - ***Modeling challenge***
    - Not in accurate modeling of one transistor (perfect match to measurement)
    - But in predictive modeling for a given technology and its process fluctuations
  - ***Multi-level circuit simulation challenge***
    - Not in simulating different types of electronic circuits (transistor/gate/block levels)
    - But in combining distinctively different algorithms in one unified simulator and applying to the same circuit described at different levels of abstraction

# Multi-Level Representation

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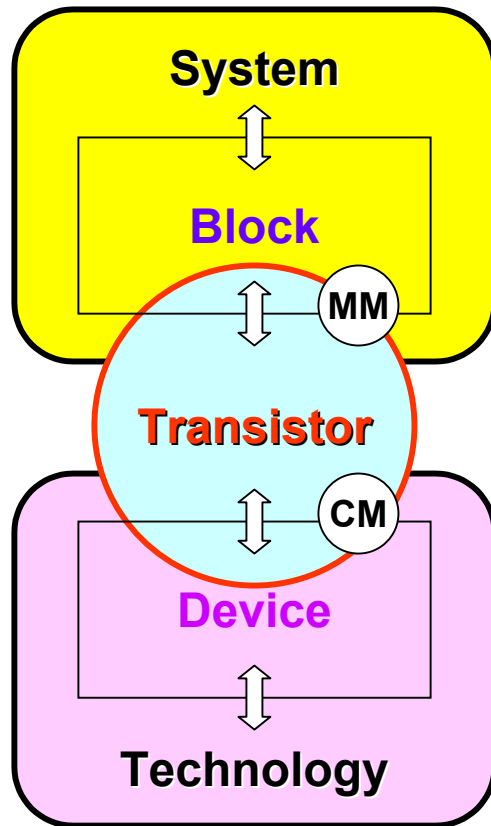
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# Multi-Level Modeling: from Technology through Device to System

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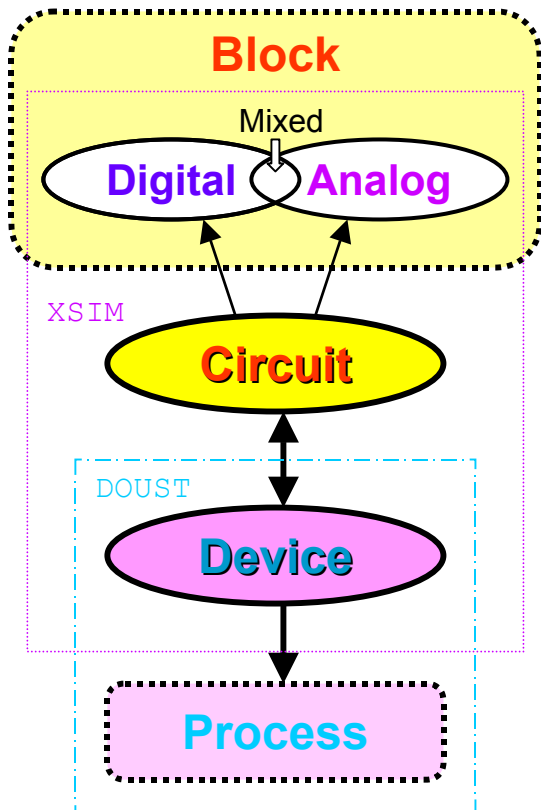
- ❑ How to “propagate” the detailed physics captured at low level to higher-level abstraction?
- ❑ Two keys to the solution:
  - **Consistent *dual-representation* at each level of abstraction**
    - Higher-level model extracted from its lower-level equivalent
    - Compact-model (**CM**) & mixed-mode (**MM**) at device/transistor/circuit level
  - **Unified *single-engine simulator environment***
    - Separate (commercial) simulators are good for their respective areas
    - But lose information when combined



# Xsim-DOUST-XSIM: Compact Model — Extraction — Circuit Simulator

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- ❑ **Xsim** — *technology-based compact model*
  - Single-piece, regional, source-referenced,  $V_t$ -based compact model
  - Separate technology ( $V_t$ -L) / transistor (I-V) modeling and characterization
- ❑ **DOUST** — *parameter-extraction program*
  - Separate process-dependent *fitting* parameters and process-variable *physical* parameters
  - Automated *one-/two-iteration* parameter extraction
- ❑ **XSIM** — *implicit mixed-signal simulator*
  - *Subcircuit-expansion* approach
  - *Automatic* digital/analog circuit partitioning
  - *Dynamic* mode switching with *dynamic delay*
- **Goal** — *a single-engine, multi-level simulator with true process-variable input for technology development and circuit design / system performance optimization*

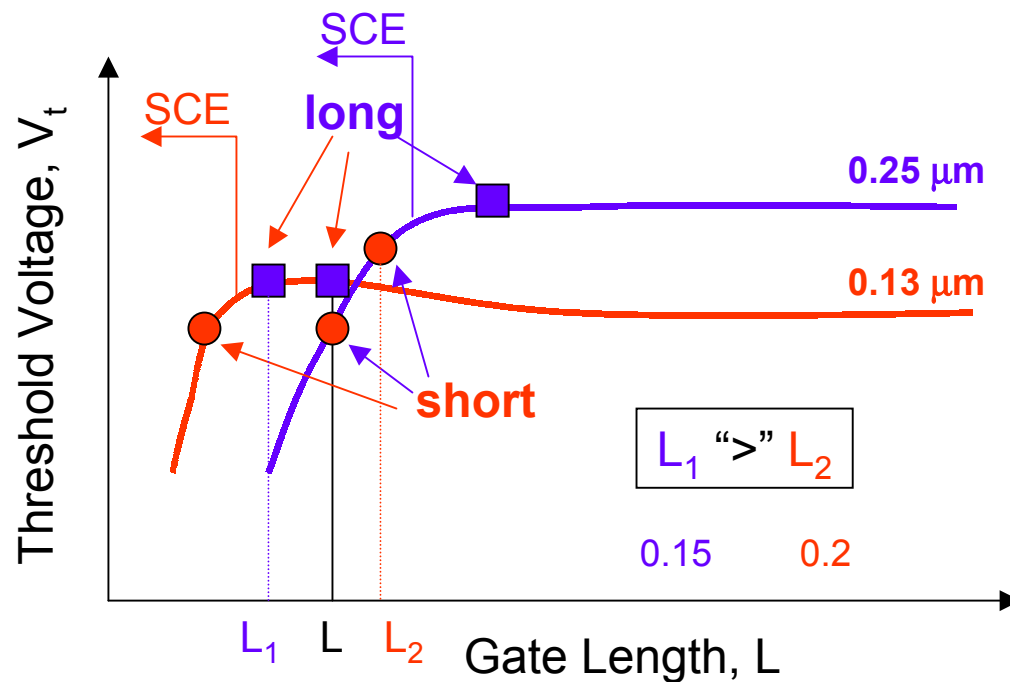
**Website:** <http://www.ntu.edu.sg/home/exzhou/Research/DOUST/>

# Long-Channel or Short-Channel?

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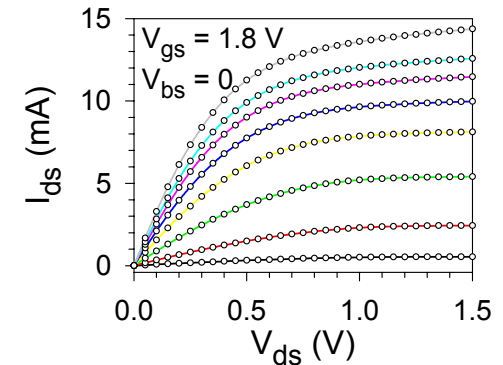
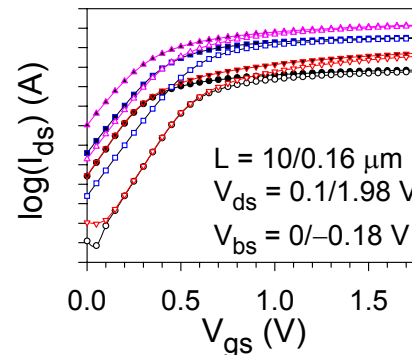
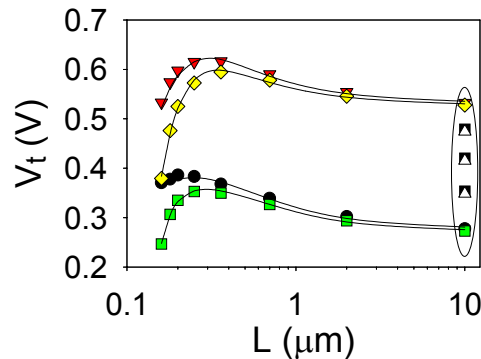
- ❑ **Short-channel effect (SCE)** — technology dependent (depends on where the device “sits” on the  $V_t - L$  curve, not the actual dimension)
- ❑ **Challenge in modeling** — geometry dependence in the SCE regime



# Separate Technology ( $V_t$ - $L$ ) and Transistor ( $I$ - $V$ ) Modeling & Characterization

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## □ Technology characterization — *technology-based model*

- Model parameters are extracted from the technology data of varying geometry at corner bias.
- $V_t$  formulation does not require knowledge of  $\mu_{\text{eff}}$  and  $R_{\text{sd}}$ ; effects are contained in the  $V_t$ - $L$  data.
- *Bias coefficients* are used to empirically model the bias-dependent model parameters.

## □ Transistor characterization — *single-transistor-based model*

- Model parameters are extracted from the electrical data of varying bias at corner geometry.
- $\mu_{\text{eff}}$ ,  $R_{\text{sd}}$ , and  $A_b$  are physically modeled and extracted at the conditions they are defined.
- *Geometry coefficients* are used to empirically model the length-dependent model parameters.



# Xsim: Physical Modeling of Linear/Saturation & Drift/Diffusion Currents

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$$I_{dsat0} = v_{sat} W C_{ox} (V_{gs} - V_t - A_b V_{dsat})$$

$$L_{eff} = L - \Delta_{CD} - 2\sigma x_j$$

$$V_{ds} \rightarrow V_{deff}$$

$$I_{ds0} = \mu_{eff} C_{ox} \frac{W}{L_{eff}} \left[ (V_{gs} - V_t) V_{deff} - \frac{A_b}{2} V_{deff}^2 \right]$$

$$V_t = V_{FB} + \phi_s + \gamma_{eff} \sqrt{\phi_{s0} - V_{bs}}$$

$$I_{deff} = \left[ 1 + (V_{ds} - V_{deff}) / V_{Aeff} \right] I_{ds0}$$

$$I_{ds0} = \mu_0 C_{ox} \frac{W}{L} \left[ (V_{gs} - V_t) V_{ds} - \frac{A_b}{2} V_{ds}^2 \right]$$

$$I_{ds} = \frac{I_{deff}}{1 + (R_{sd} I_{deff}) / V_{deff}}$$

$$I_{ds0} = \mu_{eff} C_{ox} (W / L_{eff}) V_{ge}$$

$$V_{gs} - V_t \rightarrow V_{geff}$$

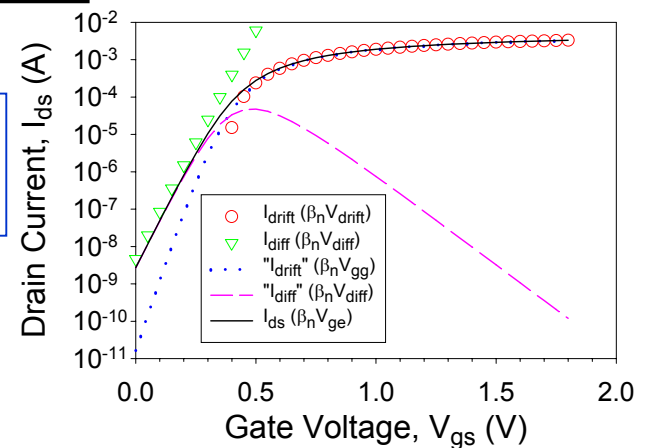
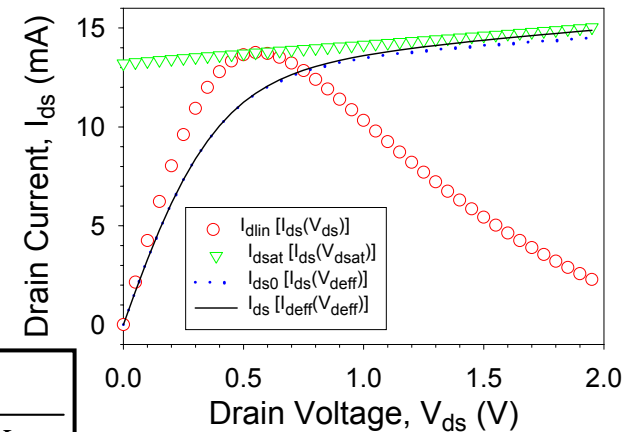
$$V_{geff} V_{de} \rightarrow V_{gg}$$

$$V_{gd} + V_{gg} \rightarrow V_{ge}$$

$$I_{ds0} = \mu_{eff} C_{ox} \frac{W}{L_{eff}} V_{geff} V_{deff} \left( 1 - \frac{A_b}{2} \frac{V_{deff}}{V_{geff}} \right)$$

$$I_{ds0} = \mu_{eff} C_{ox} (W / L_{eff}) V_{gd}$$

$$I_{diff} = \mu_0 C_{ox} \frac{W}{L} v_{th}^2 (C_d / C_{ox}) e^{(V_{gs} - V_t - V_{off}) / (n v_{th})} (1 - e^{-V_{ds} / v_{th}})$$



# DOUST: Prioritized One-/Two-Iteration Model Parameter Extraction

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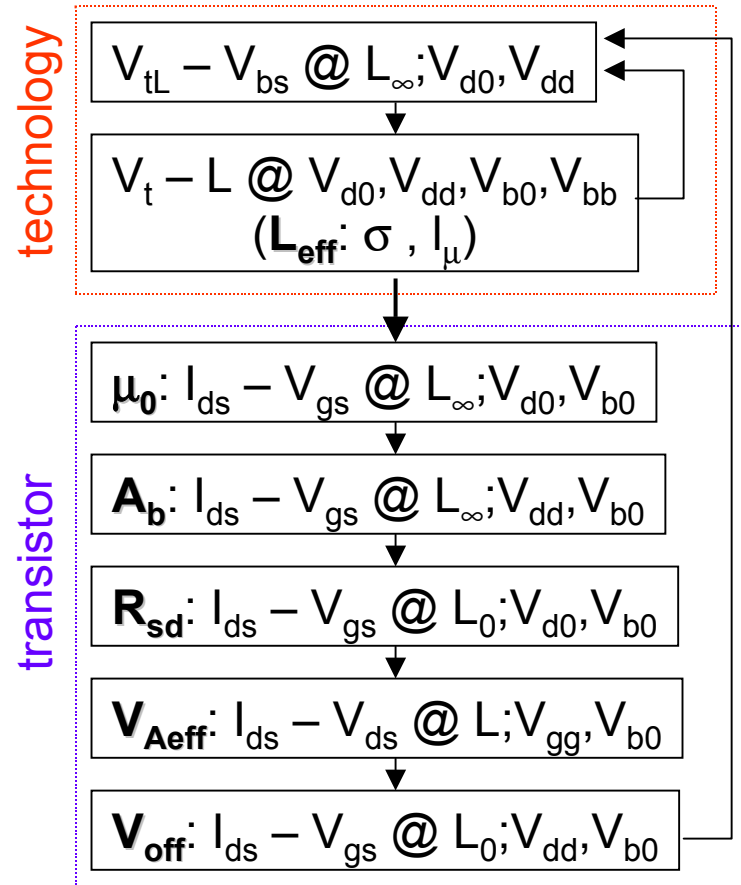
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## □ Principle assumptions

- Short-channel equations approach long-channel ones
- Un-extracted parameters should have little effect in the current step of extraction
- Once extracted, their values should be fixed; subsequent extraction should not affect what have been calibrated

## □ Errors involved

- Corner conditions not being “wide” enough
- Switching from simple to full equations
- Second iteration using full equations and first-iteration values as initial guess

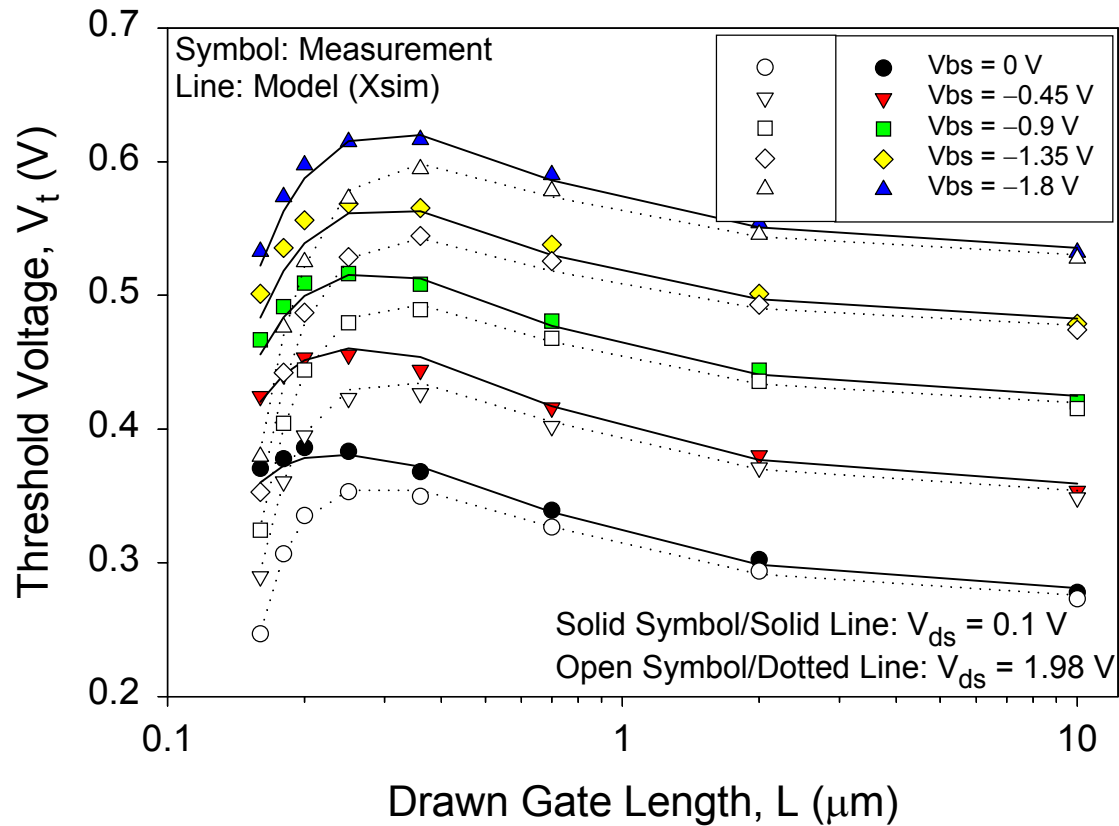


# Technology Prediction on the 0.18- $\mu\text{m}$ Technology

## Threshold Voltage Prediction

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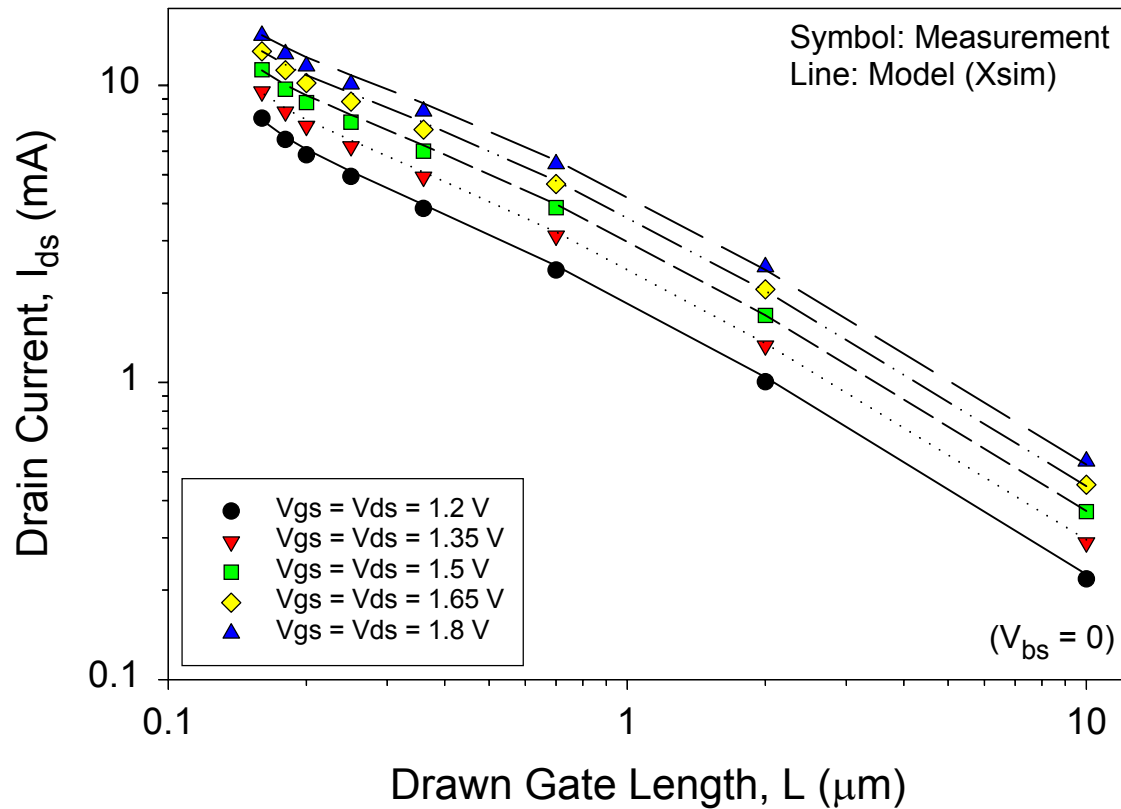


# Technology Prediction on the 0.18- $\mu\text{m}$ Technology

## Saturation Current Prediction

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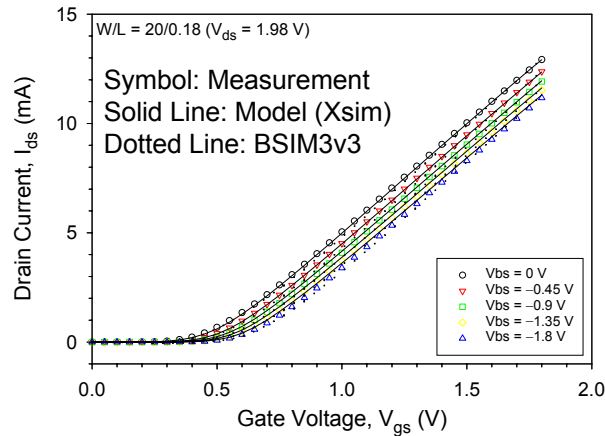
# Technology Prediction on the 0.18- $\mu\text{m}$ Technology

## Transfer (Gate) Characteristics

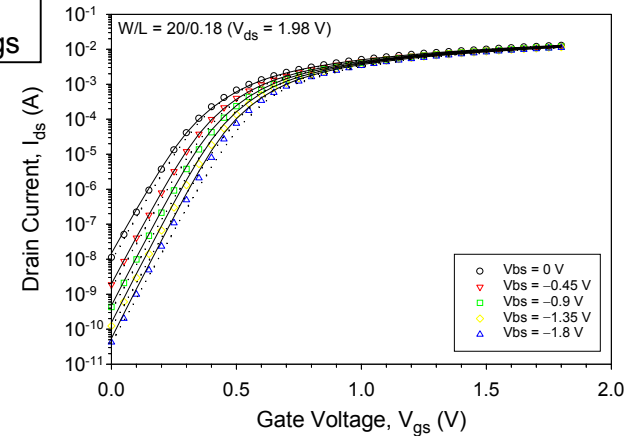
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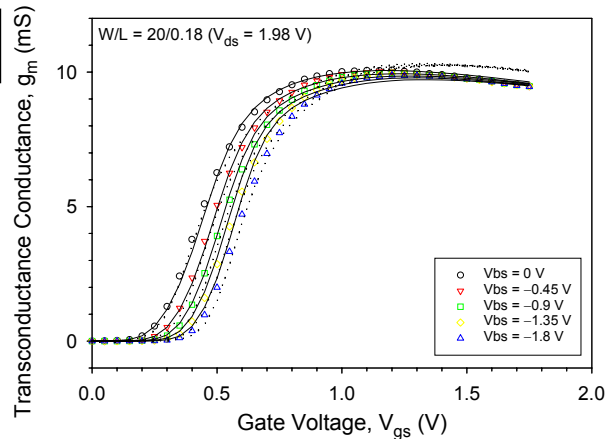
$I_{ds}-V_{gs}$



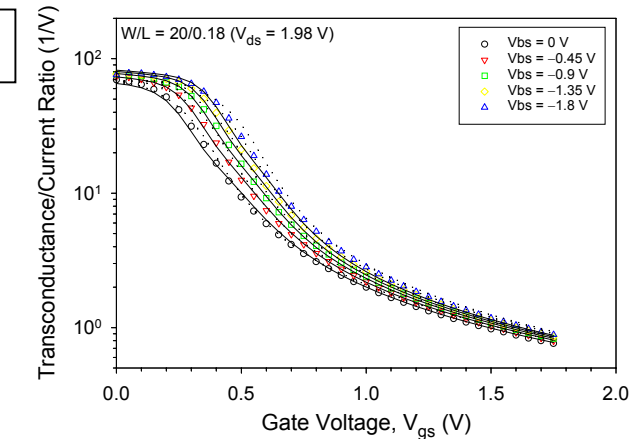
$\log(I_{ds})-V_{gs}$



$g_m-V_{gs}$



$g_m/I_{ds}-V_{gs}$





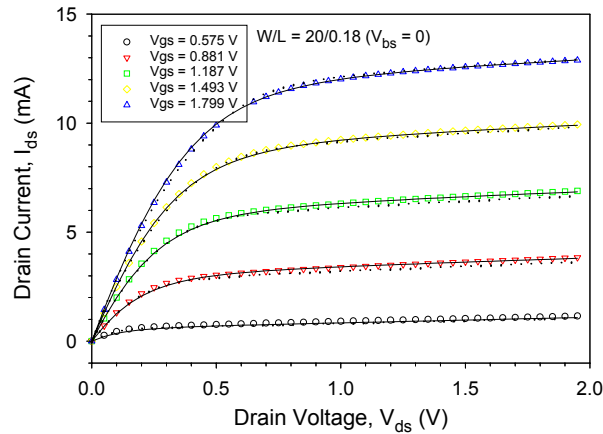
# Technology Prediction on the 0.18- $\mu\text{m}$ Technology

## Output (Drain) Characteristics

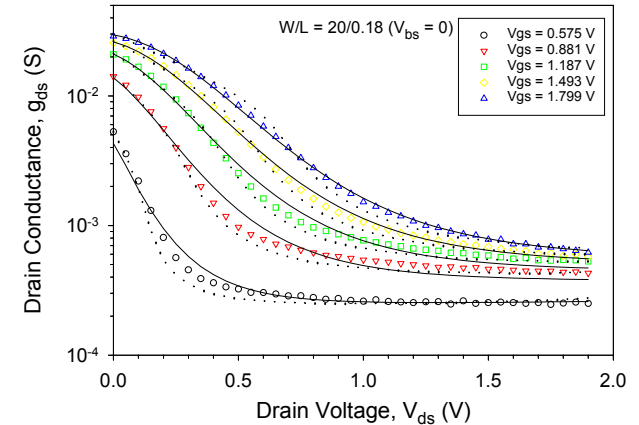
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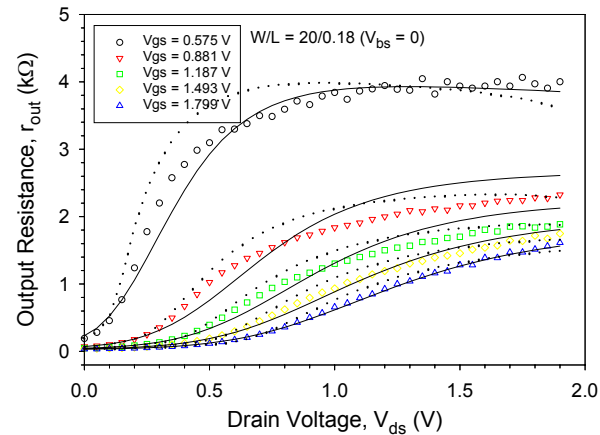
$I_{ds}-V_{ds}$



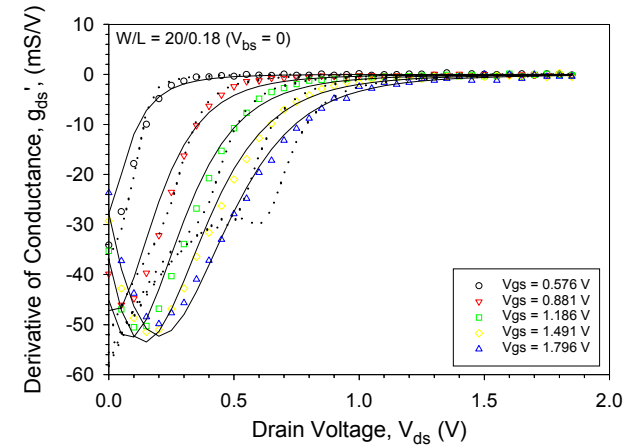
$g_{ds}-V_{ds}$



$r_{out}-V_{ds}$



$g_{ds}'-V_{ds}$



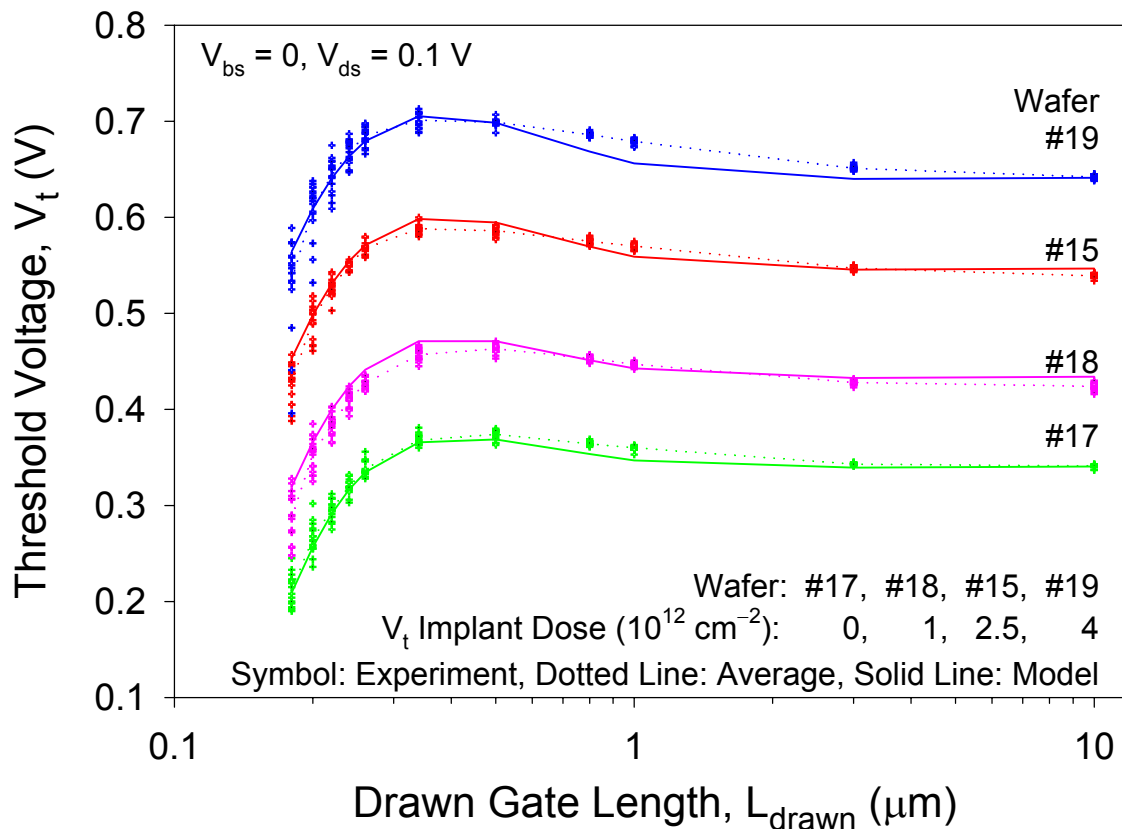
# Process Correlation on the 0.25- $\mu\text{m}$ Technology

## Threshold Voltage Prediction

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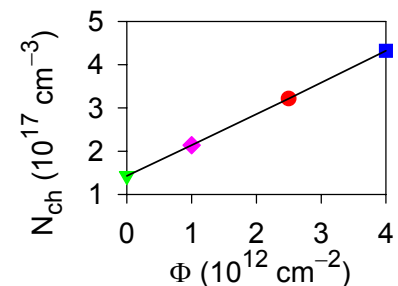
Experimental data measured from 17 sites of split-lot wafers



### Process correlation

- Using wafer #15 to calibrate  $V_t$  model
- Using long-channel  $V_t - V_{bs}$  from wafers #15/17/19 to extract  $N_{ch}$  for each wafer
- Correlating  $N_{ch}$  to  $V_t$ -implant dose  $\Phi$  with linear approximation
- Predicting  $V_t - L_{drawn}$  (especially #18) with  $\Phi$  as input

$$N_{ch} = 1.426 \times 10^{17} + 7.231 \times 10^4 \Phi$$



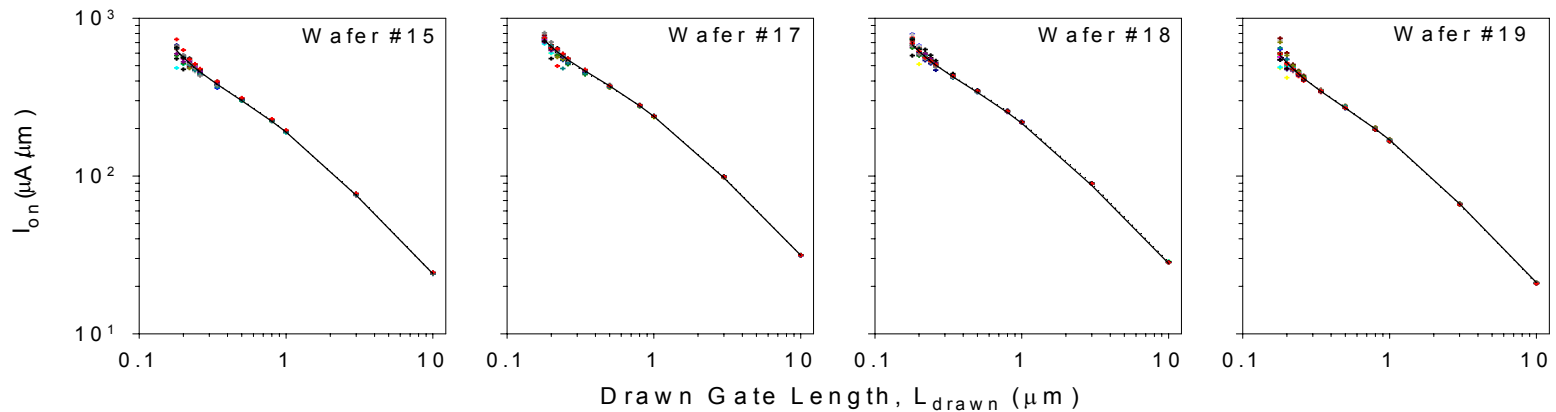
# Process Correlation on the 0.25- $\mu\text{m}$ Technology

## Saturation/leakage Current Prediction

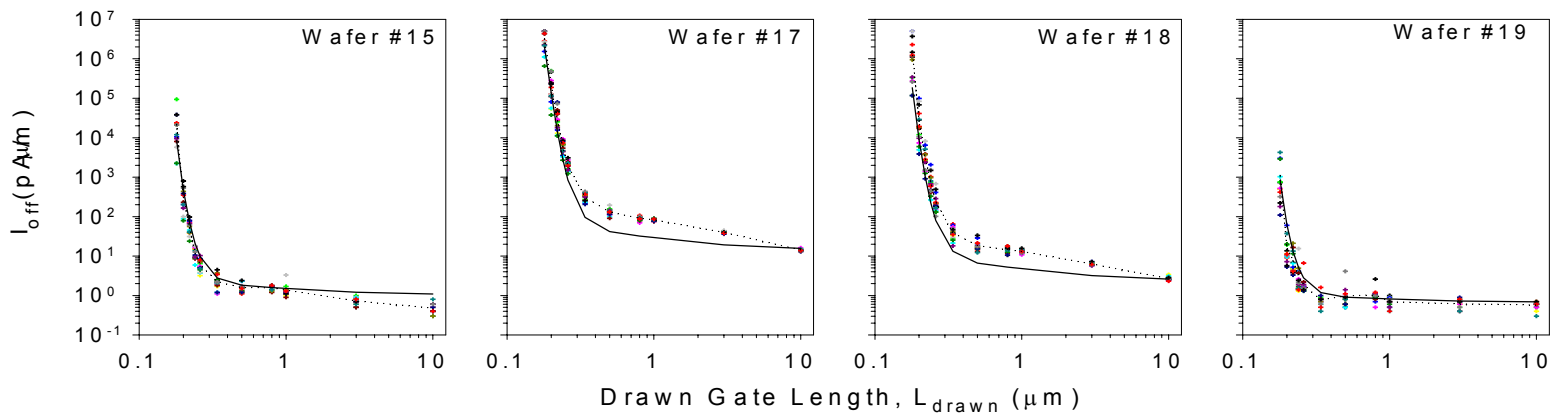
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Symbol: Measurement, Dotted Line: Average, Solid Line: Model



Symbol: Measurement, Dotted Line: Average, Solid Line: Model



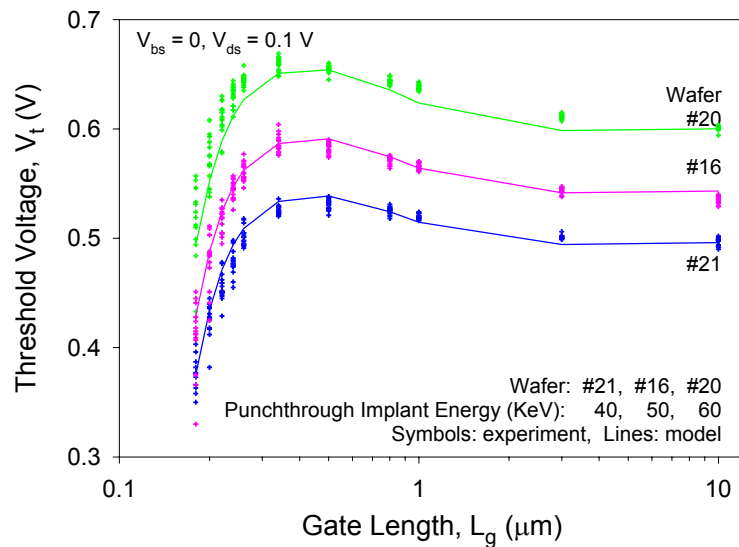
# Process Correlation on the 0.25- $\mu\text{m}$ Technology

## Punchthrough Implant Energy Correlation

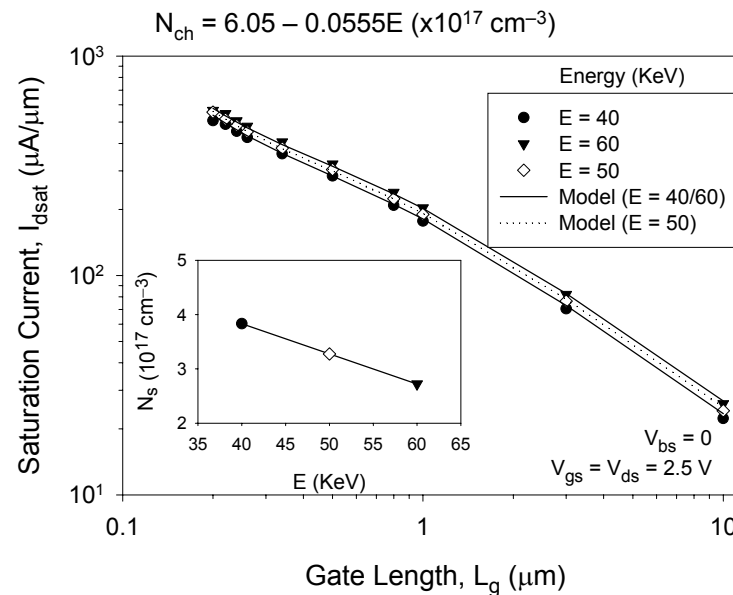
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### $V_t - L_g$ Prediction



### $I_{dsat} - L_g$ Prediction



Xsim prediction (wafer #16) with PT-implant energy as input parameter

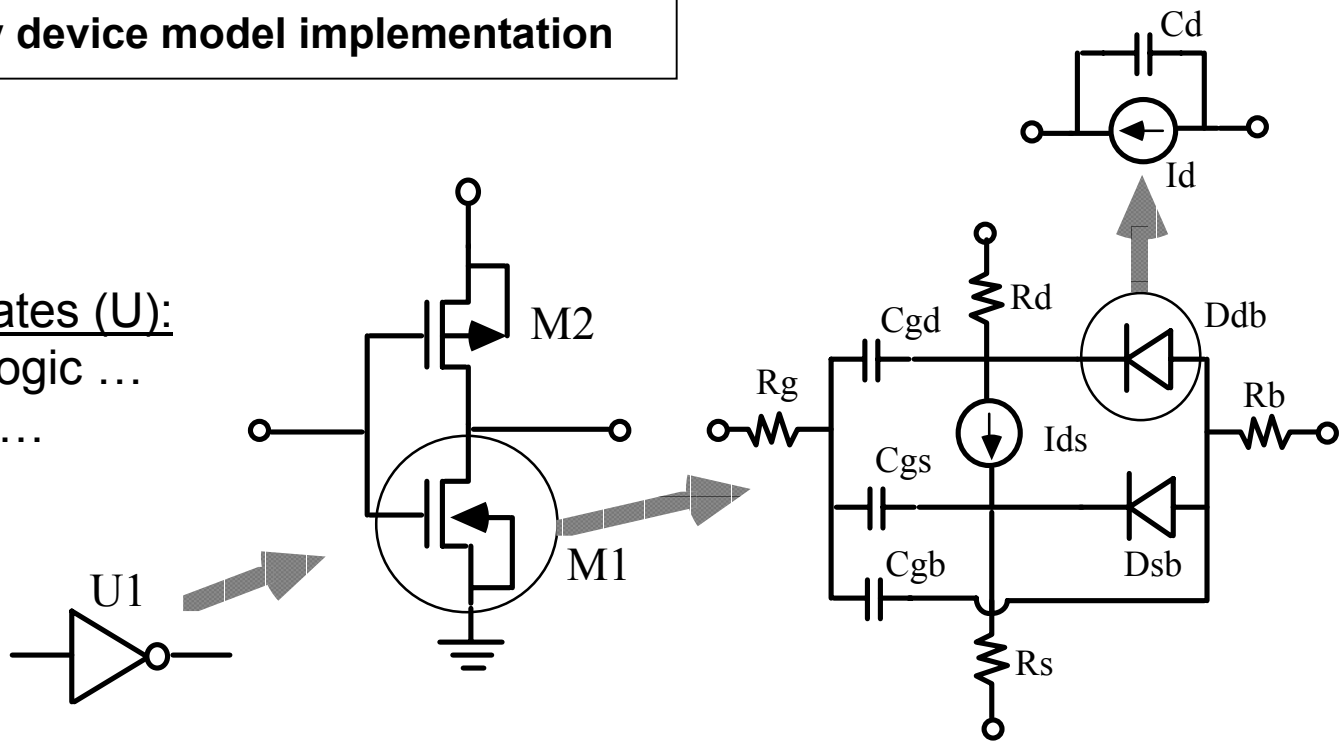
# XSIM: Subcircuit Expansion Approach

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- Natural circuit partition (BBD matrix)
- Consistent dual representation
- Easy device model implementation

Digital gates (U):  
.model logic ...  
.subckt ...

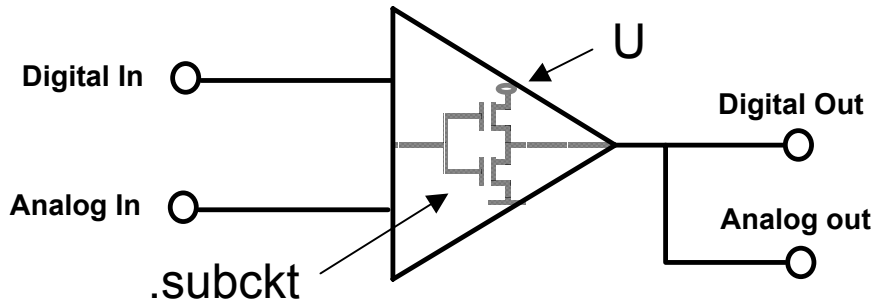




# Dynamic Partitioning and Mode Switching

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<u>Three modes:</u>	<u>As if:</u>
<code>.set mode=analog</code>	<b>X</b>
<code>.set mode=digital</code>	<b>U</b>
<code>.set mode=mixed</code>	<b>X↔U</b>

## □ Dual representation

- Each digital gate (**U**) has two representations: **logic** and **subckt**
- Higher-level (**logic**) model parameters are extracted from lower-level (**subckt**) equivalent, thus, a consistent dual-representation

## □ Accuracy–speed tradeoff

- In **analog** mode: **U** elements are simulated with “analog accuracy” (as if **X**)
- In **digital** mode: **U** elements are accelerated with “digital speed”
- In **mixed** mode: **U** elements are switching between **analog** and **digital**, at run time, depending on the “quality” of the input signal

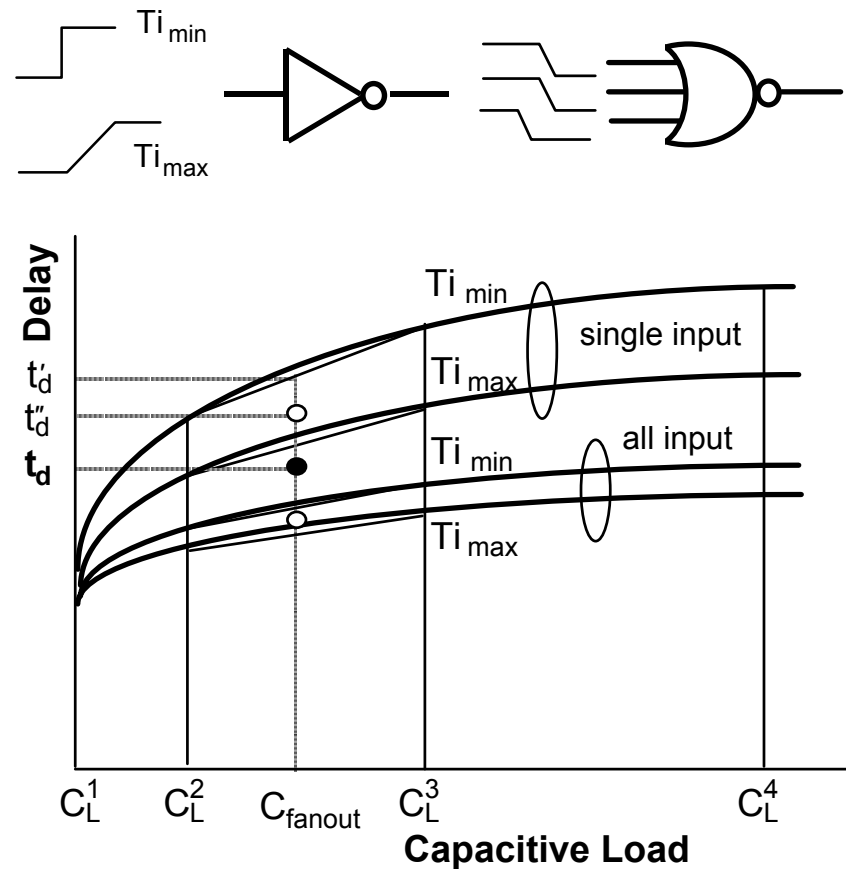
➤ **An “implicit”/automatic/dynamic mixed-signal simulator**

# Dynamic-Delay Model

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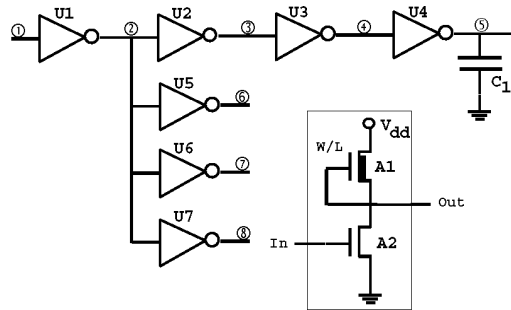
- ❑ **Delay depends on:**
  - Load capacitance (user-netlist)
  - Input transition time (run-time)
  - Input triggering (run-time)
- ❑ **Logic parameters**
  - Input/output capacitances
  - Intrinsic delays, rise/fall times
- ❑ **Dynamic-delay model**
  - **Nonlinear load dependence:**  
N-breakpoint algorithm
  - **Input-slope dependence:**  
Linear interpolation/extrapolation
  - **Multiple-input triggering:**  
Single-/all-input triggering
- *Pre-calculated by simulating the full-subcircuit & stored in .model*



# Comparison of Different Delay Models

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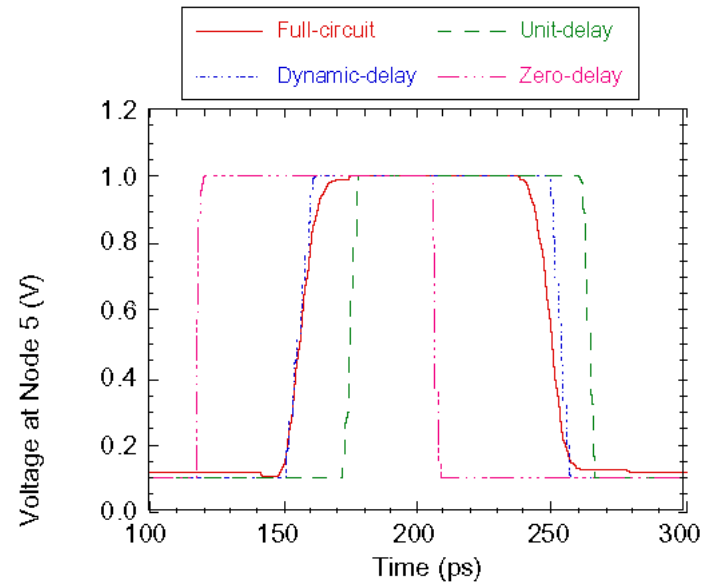
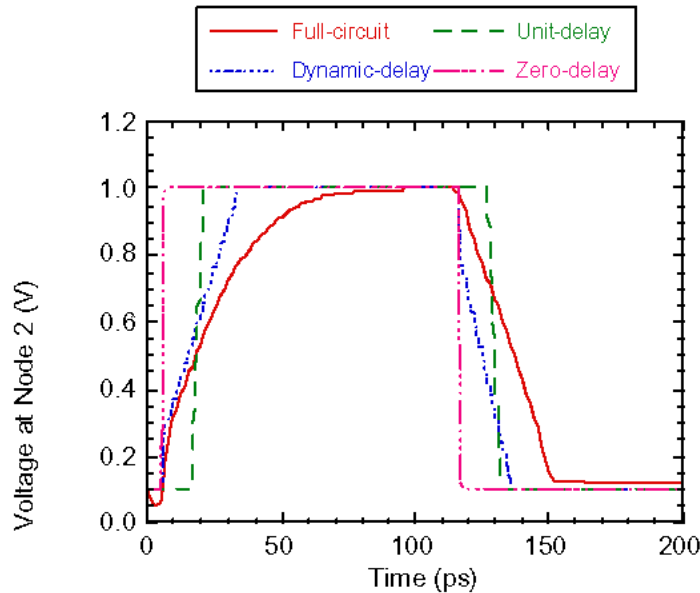


## Fanin capacitance:

Cin1-4 = 4.48 fF  
 Cin5 = 4.64 fF  
 Cin6 = 4.33 fF  
 Cin7 = 4.20 fF

## CPU time (s):

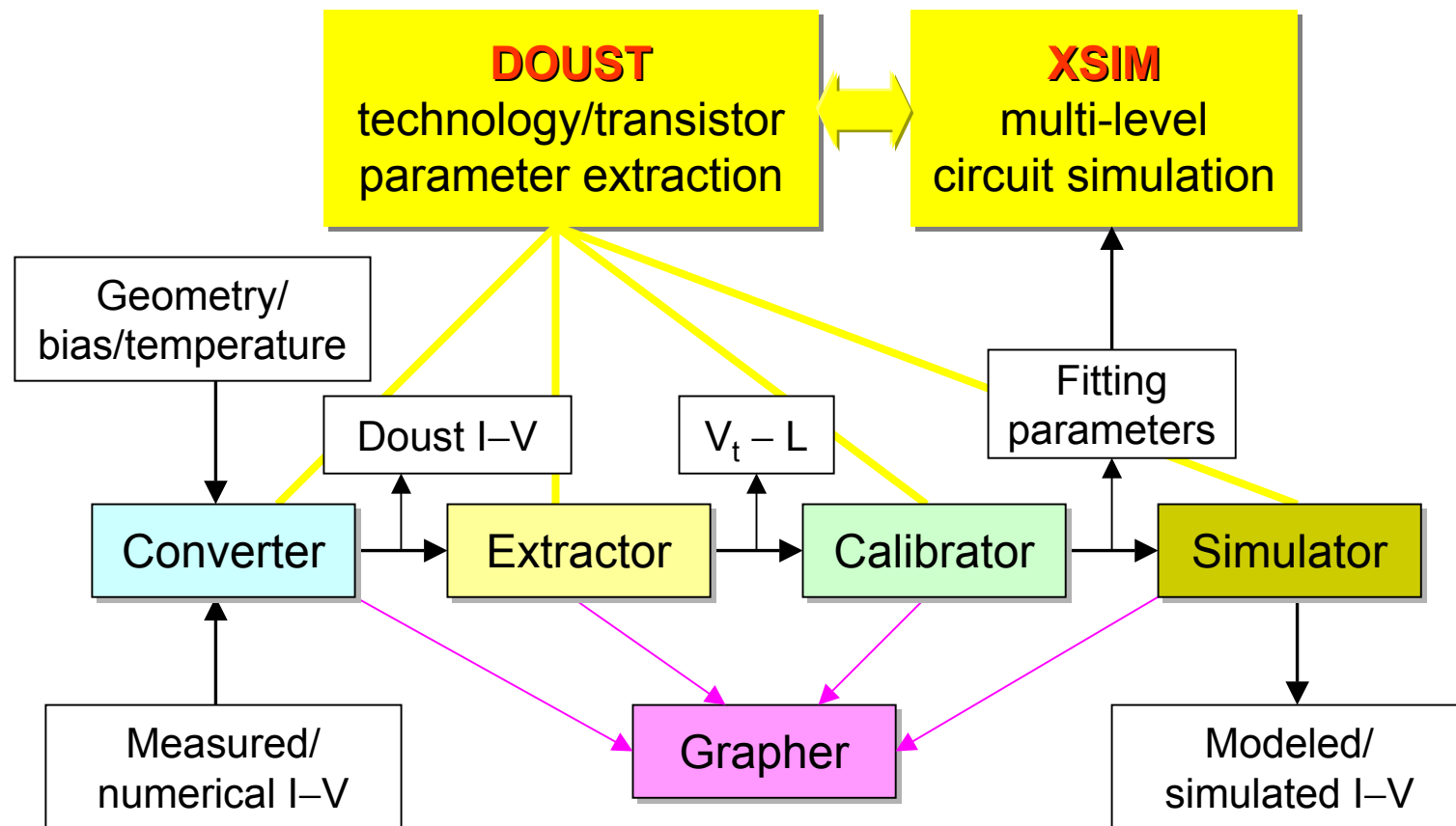
Full-circuit = 21.86  
 Dynamic-delay = 3.89  
 unit-delay = 3.61  
 zero-delay = 3.54



# DOUST: Design and Optimization of *Ultra-Small Transistors*

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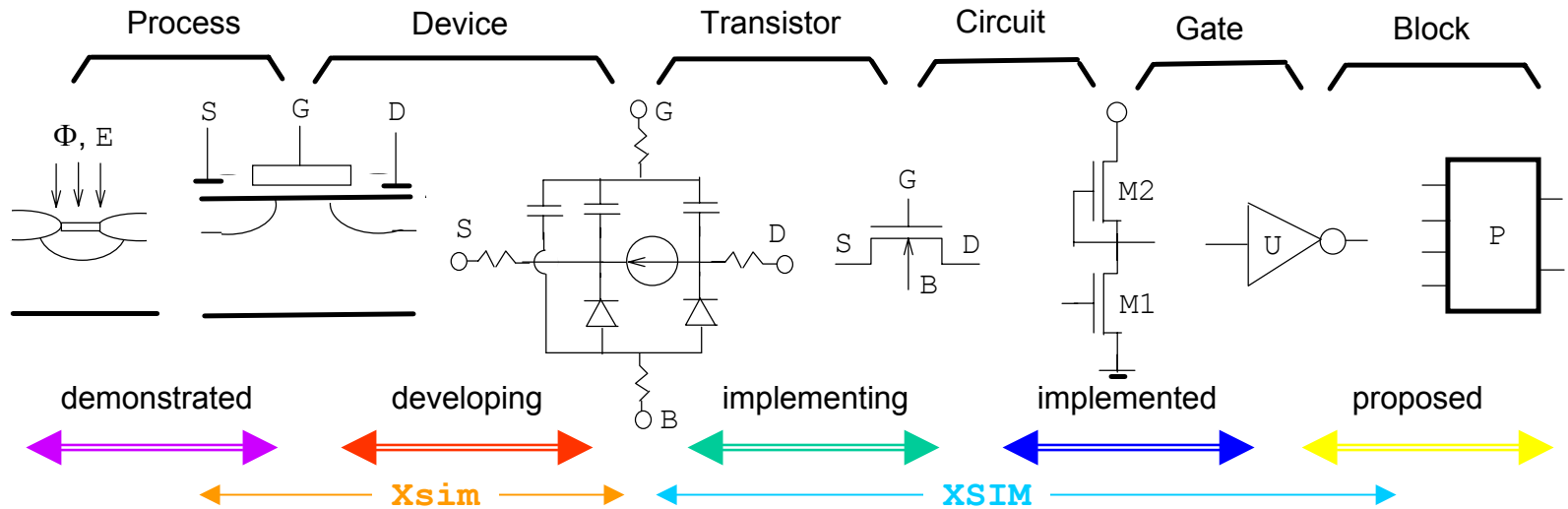
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# Multi-Level Modeling with Dual Representation: From Process Through Device/Circuit to System

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<u>Device Level</u>	<u>Transistor Level</u>	<u>Gate Level</u>	<u>Block Level</u>
<b>.model</b>	<b>Mxx</b> <Nd> <Ng> <Ns>	<b>Uxx</b> <Nref> <Nout> <Nin1>	<b>Pxx</b> <Nref> <Nout1>
+ <Mname>	+ <Mname> <L> <W>	+ [<Nin2> ...] <Family>	+ [<Nout2> ...] <Nin1>
+ <b>nmos</b>	<b>.subckt</b> <Cktname>	+ <Type><n> <Cktname>	+ [<Nin2> ...] <Blk_name>
+ [param-list]	+ <N1> [<N2> ... ]	<b>.model</b> <Family><Type><n>	+ <Blk_type> <Ckt_name>
:	+ [param-list]	+ <N1> [<N2> ... ] <b>logic</b>	<b>.model</b> <Blk_name> <b>block</b>
+ [process-vars]	<b>.ends</b>	+ cap1 drms dfxa ... [param-list]	+ [param-list]



# Conclusions

## ❑ Multi-level modeling environment

- **Compact Model** (CM) is at the core of the modeling hierarchy, as it bridges between a given technology and circuit design and determines the accuracy/speed tradeoff.
- Centered at the **transistor** level, “push down” to **technology** level for process correlation, and “push up” to **block** level for system performance optimization.

## ❑ Dual representation in single engine

- The key to having a consistent multi-level solution is to have a **dual-representation** at each level.
- The key to establishing the link between the technology developers and circuit designers lies in the development of a **single-engine** tool.

## ❑ Vision

- A compact model for technology developers
- A circuit simulator with process-variable input